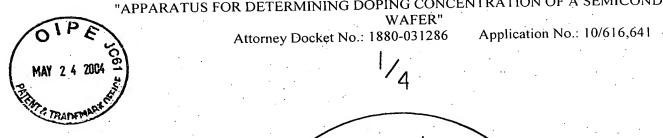
Inventor: William H. Howland
"APPARATUS FOR DETERMINING DOPING CONCENTRATION OF A SEMICONDUCTOR



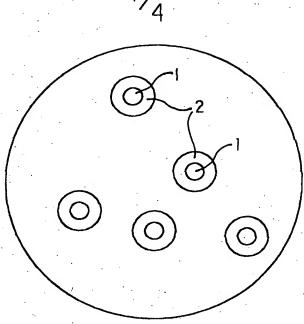
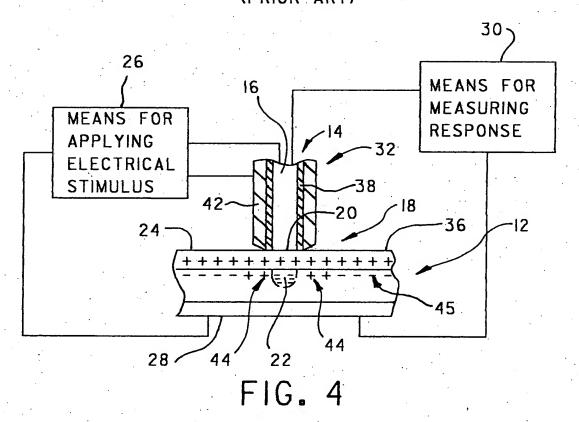


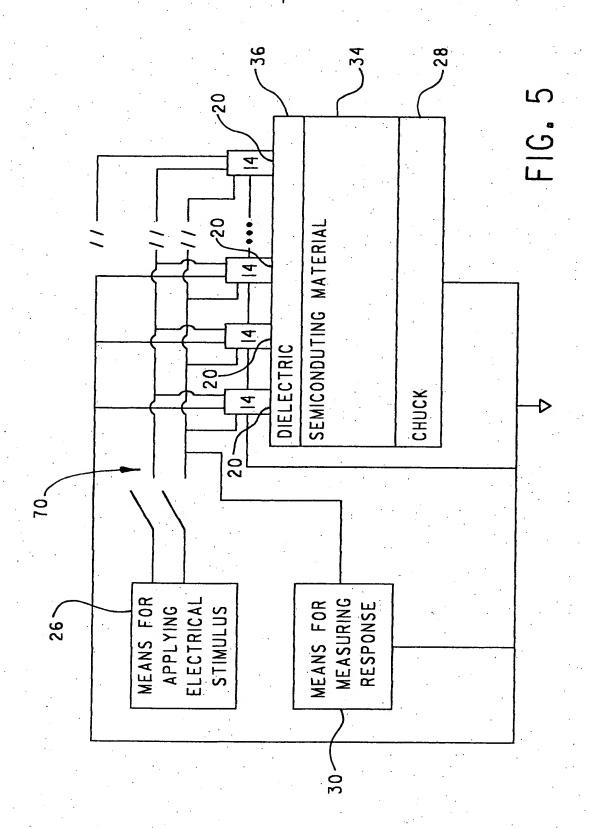
FIG. 1
(PRIOR ART)



Inventor: William H. Howland
"APPARATUS FOR DETERMINING DOPING CONCENTRATION OF A SEMICONDUCTOR
WAFER"

Application No.: 10/616,641 Attorney Docket No.: 1880-031286 MEANS FOR **MEASURING** 26 **RESPONSE** MEANS FOR SHAFT 16 APPLYING **PROBE** ELECTRICAL PROBE GUARD STIMULUS **ELEMENT 32** DISTAL END 18. CONDUCTIVE : **TIP 20** SURFACE 24 **OBJECT** SEMICONDUCTOR CHUCK-AREA 22 28 WAFER 12 FIG. 2 MEANS FOR **MEASURING** RESPONSE 38 20-MEANS FOR 24 -APPLYING ELECTRICAL 34 STIMULUS -26 28 18 FIG. 3

Attorney Docket No.: 1880-031286 Application No.: 10/616,641



Inventor: William H. Howland
"APPARATUS FOR DETERMINING DOPING CONCENTRATION OF A SEMICONDUCTOR
WAFER"

Attorney Docket No.: 1880-031286

Application No.: 10/616,641

4/4

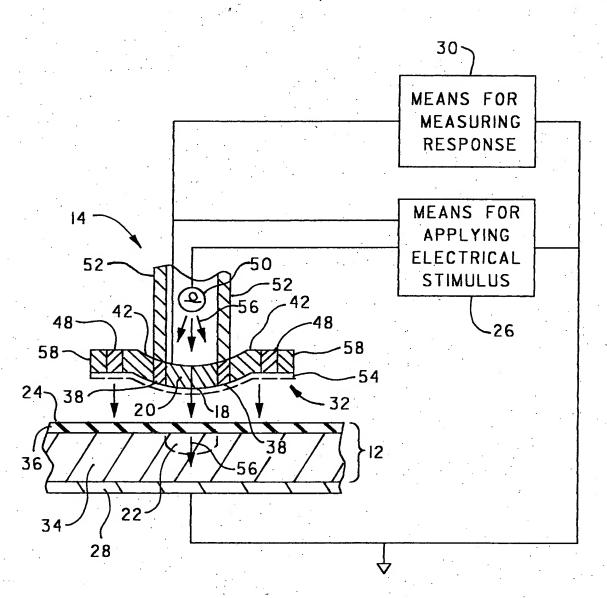


FIG. 6